IN THE CLAIMS:

Please amend Claims 1, 2, 8, 13 and 20 as follows:

(Twice Amended) A gas laser device / comprising: 1.

a chamber for sealingly storing a laser gas therein[, and for producing light amplification through reflection of light between a total reflection window and an exit/window];

a discharging electrode for exciting the laser gas through electrical [discharge, so that laser light is outputted from said chamber] discharging;

a total reflection mirrox for amplifying laser light produced by the electrical discharging from said discharging electrode;

an output window for amplifying the laser light and for outputting a portion of/the laser light amplified between said total reflection mirror and said output window;

a blower for circulating the laser gas within said chamber, so that the Aaser gas passing an electrical discharging region of said discharging electrode is circulated in said chamber and is refurned to the electrical discharging region of said discharging electrode; and

control means for [changing] controlling revolutions of said blower [between (i) an in-operation state in which the

laser gas is excited by in accordance with a state of the electrical [discharge] discharging from said discharging electrode [and] so that the [laser light is being outputted, and (ii)] revolutions of said blower a stand-by state [in which no laser light is emitted, but an output of the laser light is being prepared] are made less than the revolutions in an in-operation state, wherein the stand-by state is a state in which no laser gas is excited by the electrical discharging from said discharging electrode and thus no laser light is emitted whereas an output of the laser light is being prepared, and wherein the in-operation state is a state in which the laser gas is excited by the electrical discharging from said discharge electrode and the laser light is being outputted.

2. (Twice Amended) A gas laser device according to Claim 1, wherein said control means [stops] controls the revolutions of said blower when said gas laser device is in the stand-by state by stopping the blower.

8. (Twice Amended) A gas laser device according to Claim 7, wherein said control means [stops] controls the revolutions of said blower when said gas laser device is in the stand-by state by stopping the blower.

13. (Twice Amended) An exposure apparatus, comprising:

a laser light source having (i) a chamber for sealingly storing a laser gas therein [and for producing light amplification through reflection of light between a/total reflection mirror and an exit window], (ii) a discharging electrode for exciting the laser gas through electrical [discharge so that laser light is outputted from said chamber] discharging, [and] (iii) a total reflection mirror for amplifying laser light produced by the electrical discharging from said discharging electrode, (iv) an output window for amplifying the laser light and for outputting a portion of the laser light amplified between said total reflection mirror and said output window, and (v) a blower for circulating the laser gas within said chamber so that the laser gas passing an electrical discharging region of said discharging electrode is circulated in said chamber and is returnéd to the electrical discharging region of said discharging electrode;

a main assembly for exposing a substrate to the laser light from said laser light source; and

control means for [changing] controlling revolutions of said blower [between (i) an exposure-operation state of said exposure apparatus in which exposure of the substrate to the laser light from said laser light source can be performed through

& X

My 1

said main assembly, and (ii) a non-exposure-operation state of said exposure apparatus] in accordance with a state of electrical discharging of said discharging electrode, so that the revolutions of said blower in a non-exposure-operating state of the exposure apparatus are made less than the revolutions in exposure operation state of the exposure apparatus, wherein the non-exposure operation state is a state in which no laser gas is excited by the electrical discharging from said discharging electrode and thus no laser right is emitted whereas an output of the laser light is being prepared, and wherein the exposure operation state is a state in which the laser gas is excited by electrical discharging from said discharging electrode and the laser light is being outputted.

20. (Twice Amended) A semiconductor device manufacturing method comprising:

sealingly storing a laser gas in a chamber[, and producing light amplification through reflection of light between a total reflection window and an exit window];

exciting, using a discharging electrode, the laser gas through electrical discharge[, and outputting laser light from the chamber];

Christ of the Ch

Carpo Os

amplifying laser light produced by the electrical discharging from said discharging electrode by a total reflection mirror;

amplifying the laser light by an output window and outputting a portion of the laser light amplified between said total reflection mirror and said output window;

circulating, using a blower, the laser gas within the chamber, so that the laser gas passing an electrical discharging region of the discharging electrode is circulated in the chamber and is returned to the electrical discharging region of the discharging electrode; and

[changing, using control means,] controlling
revolutions of the blower [between (i) an in-operation state in
which the laser gas is excited by the electrical discharge from
the discharging electrode and the laser light is being outputted,
and (ii) a stand-by state in which no laser light is emitted, but
an output of the laser light is being prepared] in accordance
with a state of electrical discharging from said discharging
electrode, so that the revolutions of the blower in a stand-by
state are made less than the revolutions in an in-operation
state, wherein the stand-by state is a state in which no laser
gas is excited by the electrical discharging from said
discharging electrode and thus no laser light is emitted whereas
an output of the laser light is being prepared, and wherein the

10 PM